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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Shinsuke SADAMITSU, et al.
SERIAL NO.: NEW U.S. PCT APPLICATION
FILED: HERewith
INTERNATIONAL APPLICATION NO.: PCT/JP03/08333
INTERNATIONAL FILING DATE: June 30, 2003
FOR: HIGH-RESISTANCE SILICON WAFER AND PROCESS FOR PRODUCING THE SAME

REQUEST FOR CONSIDERATION OF DOCUMENTS
CITED IN INTERNATIONAL SEARCH REPORT

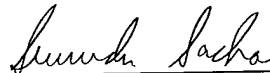
Commissioner for Patents
Alexandria, Virginia 22313

Sir:

In the matter of the above-identified application for patent, notice is hereby given that applicant(s) request that the Examiner consider the documents cited in the International Search Report according to MPEP §609 and so indicate by a statement in the first Office Action that the information has been considered. When the Form PCT/DO/EO/903 indicates both the search report and copies of the documents are present in the national stage file, there is no requirement for the applicant(s) to submit them (1156 O.G. 91 November 23, 1993).

Respectfully submitted,

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